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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:  
**Saka et al.**

Application Number: **10/029,080**

Filed: **December 21, 2001**

For: **In-Situ Method and Apparatus  
for End Point Detection in  
Chemical Mechanical Polishing**

Group Art Unit: **2877**

Examiner: **M. P. Stafira**

CERTIFICATE OF MAIL (37 CFR 1.8(a))

I hereby certify that this paper (along with any referred to as being attached or enclosed) is being deposited with the United States Postal Service with sufficient postage as First Class Mail in an envelope addressed to: Commissioner for Patents, Washington, DC 20231 on September 18, 2003.

Signed: 

Lori Cox


**TRANSMITTAL FOR RESPONSE/AMENDMENT**

Commissioner for Patent  
P.O. Box 1450  
Alexandria, VA 22313-1450  
Sir:

Please find enclosed the following documents relating to the subject patent application:

- ☒ Amendment in response to Office Action dated April 18, 2003;
- ☒ Amendment/Response;
- ☒ Petition for Two (2) Month Extension of Time;
- ☒ A check in the amount of \$410.00 for Extension of Time Fee and \$126.00 for additional claims;
- ☒ Please charge any additional fees or credit any overpayment to Deposit Account No.50-2319 (Order No. A-69174-1/MSS/MDV (463035-29)); and
- ☒ Stamp addressed return postcard.

Respectfully submitted

  
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